

**SEC.584**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re PATENT APPLICATION of

Ki-sang KIM et al.

Group Art Unit: 1763

Serial No.: 09/237,229

Examiner: Lund, J.

Filed: January 26, 1999

**MULTI-CHAMBER SYSTEM HAVING COMPACT INSTALLATION SET-UP FOR AN ETCHING FACILITY FOR SEMICONDUCTOR DEVICE MANUFACTURING**

**PRELIMINARY AMENDMENT**

Honorable Assistant Commission of Patents and Trademarks,  
Washington, D.C. 20231

Date: June 30, 2000

Sir:

Preliminary to the examination of the above-identified application, please enter the following amendments and remarks.

**In the Specification:**

Kindly amend the specification as follows:

Page 20, line 7, change "means" to --car--.

**In the Claims:**

Please amend the claims as follows:

1. (Amended) A multi-chamber system of an etching facility for manufacturing semiconductor devices comprising: